

TECHNICAL SPEC FOR Stepper 2 (tool not complete)

System Model:

Canon FPA 2000 i1, SN : 205 268i1

Tool has been shut down by Litho tech.

Electricity, cooling water, Vacuum and CCA are closed.

Cables between Main unit and power box are still connected, locking kit and demounting for be provided by buyer.

Wafer size: 6 inch

Wafer type: Jeida flat

Chuck type: Ring chuck

Reticle changer type: I1 box 14 reticles, standard

Inline right or left: Left

Particle checker (PPC): NO

Touch panel type: Canon standard

Options: None

Reticle size: 5 inch

Reticle alignment: Reticle rotation repeatability ≤ 0.03 um

Wafer alignment: ≤ 0.15 um

Auto focus: ≤ 0.15 um

Auto feeder: Yes

Wafer tilt:

Wafer feeder:

Track interface: Yes (stepper was used inline with track, track interface is track part

Laser: HeNe

Lens data:

Stage and U-lens at shutdown

Intensity: 250 mW/cm²

Distortion: ≤ 0.07 μ m

Uniformity: 7.5%

Used for 0.35micron line and space? No

Chuck maintenance tool: No

Reticle bar code reader: Yes

Cassette bar code reader: No

SW Version:

OS:

Vintage:1993

Missing/defective parts: Several missing parts